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Type of paper transmitted: Letter to the Patent and Trademark
OfficeApplicant's Name: Henry F. Erk et al.Serial No.: 10/665,982 Examiner: Eric Brice ChenFiling Date: 09/18/2003 Art Unit: 1765 Confirmation No.: 5374Application Title: PROCESS FOR ETCHING SILICON WAFERSIF YOU DO NOT RECEIVE ALL PAGES CLEARLY, CALL BACK AS SOON AS
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MEMC 02-0051 (3032.1)
PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of Henry F. Erk et al.
Serial No. 10/665,982
Filed September 18, 2003
Confirmation No. 5374
For PROCESS FOR ETCHING SILICON WAFERS
Examiner Eric Brice Chen

Art Unit 1765

February 13, 2006

LETTER TO THE PATENT AND TRADEMARK OFFICE

TO THE COMMISSIONER FOR PATENTS,

SIR:

In response to the Office action mailed November 16, 2005,
please consider the following remarks.

Remarks begin on page 2 of this Letter.